Cavity Processing Facility

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Outline



- Establishing the Need for this Facility
- Process Definition
- Cavity Processing Facility (CPF) Scope and Infrastructure Requirements
- CPF Cost Estimate
- CPF Schedule
- Conclusion

Goals for SRF Infrastructure: CPF



- To perfect U.S. fabrication & processing of SRF cavities and modules and to demonstrate performance with a full range of testing (including beam)
 - Deploy ILC design / processing / assembly techniques
 - Establish process controls to reliably achieve high gradient cavity operation and module performance
 - Test cavities and modules at the component level and in a systems test to demonstrate yield, reproducibility and beam performance
- To facilitate commercial production of SRF components and modules



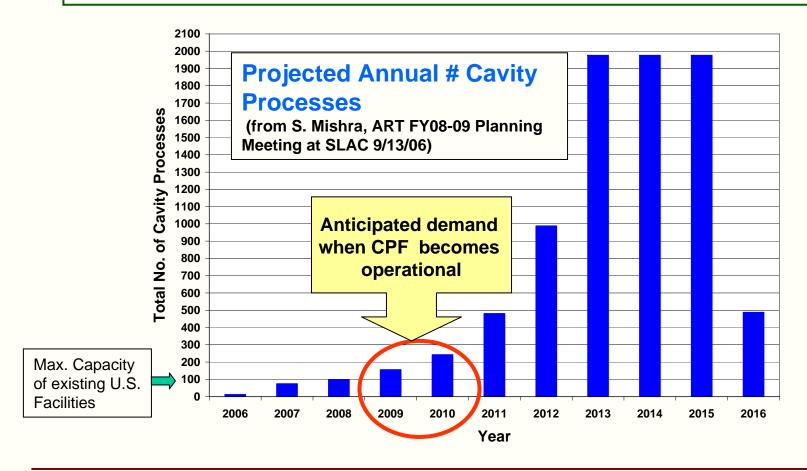
- Train and transfer SRF technology to the US industry
- Allow industrial participation and input to the process
 - Similar to SC cable and magnet technology transfer
- To participate in SRF Research and Development
 - Develop expertise in SRF technology and provide training base for construction and operation of future accelerators
 - Our attempt to fit into the world's SRF community

All of this work will be carried out with US/international collaboration

Establishing the Need for this Facility



• Existing U.S. capability is insufficient to meet the anticipated demand---as demonstrated in Shekhar's talk



US Laboratories Capacity



| Program | FY07 | FY08 | FY09 | FY10 | Capacity Needed/yr by FY10 |
|-----------------------------------|--------------------------------------|--------------------------------------|--|---|----------------------------------|
| Cavity Processing (EP, HPR, Bake) | Jlab-30 Cornell-10 | Jlab-40 Cornell-10 ANL-40 | Jlab-40 Cornell-10 ANL-40 Fermilab-20 | Jlab-40 Cornell-10 ANL-40 Fermilab-100 | 200 |
| Vertical Testing | Jlab-30 Cornell-10 Fermilab-20 | Jlab-40 Cornell-10 Fermilab-75 | Jlab-40 Cornell-10 Fermilab-75 | Jlab-40 Cornell-10 Fermilab-200 | 200 |
| Horizontal Testing | Fermilab-6 | Fermilab-24 | Fermilab-24 | Fermilab-72 | 72 |
| Cryomodule Assembly | Fermilab-1 | Fermilab-4 | Fermilab-12 | Fermilab-12 | 12 |
| Cryomodule Test | Fermilab: ILCTA_NML | Fermilab: ILCTA_NML | Fermilab: ILCTA_NML | Fermilab: ILCTA_NML CMTS | 12 |

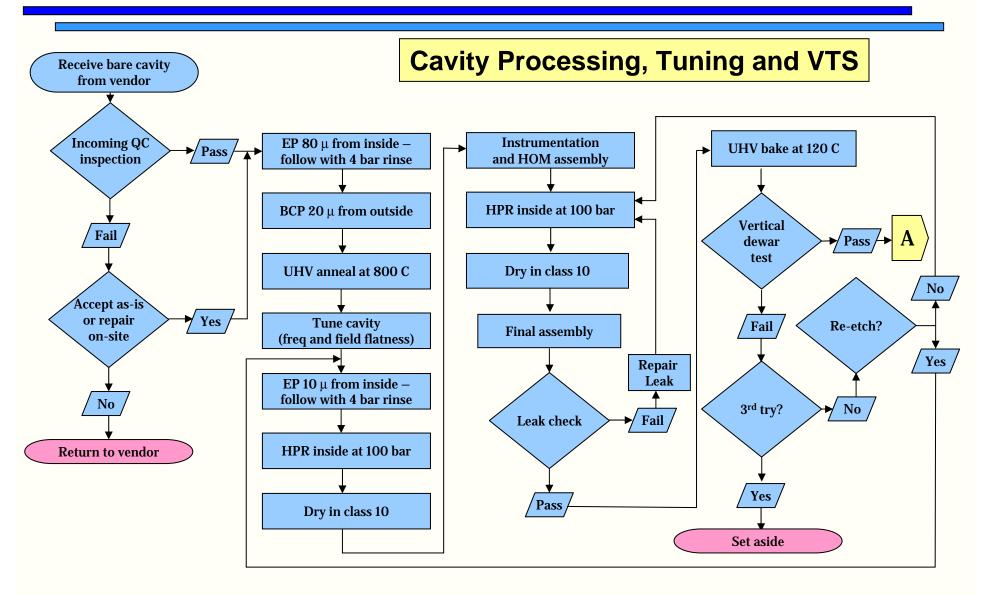
Process Definition



- The term "process" defines the complete procedure that transforms a fabricated cavity into a fully qualified cavity at a specified operating gradient and quality factor (in our case 35MV/m and 1.0e10). It includes the following operations:
 - Cavity processing
 - Cavity tuning
 - Vertical testing
- A flow chart delineating the procedure is presented on the next slide

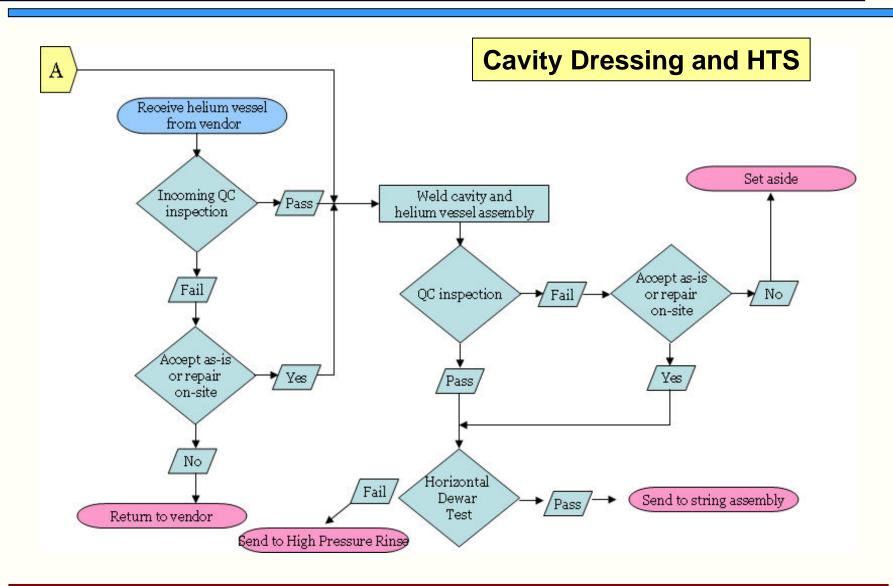
Process Flow Chart





Cavity Flow Chart Subsequent to Completing the Process Flow Chart





CPF Functions



- Perform pre-EBW etching of cavity components
- Receive and store fabricated cavities
- Perform mechanical inspection of cavities
- Perform internal and external chemical processing
- Perform high pressure rinsing
- Perform high and low temperature cavity bakes
- Tune cavities for fundamental frequency and field flatness
- Prepare cavity for vertical test
- Receive vertically tested cavities
- Install helium vessels (dress cavities)
- Prepare dressed cavities for horizontal testing
- Receive cavities from HTS and send to string assembly facility (CAF)

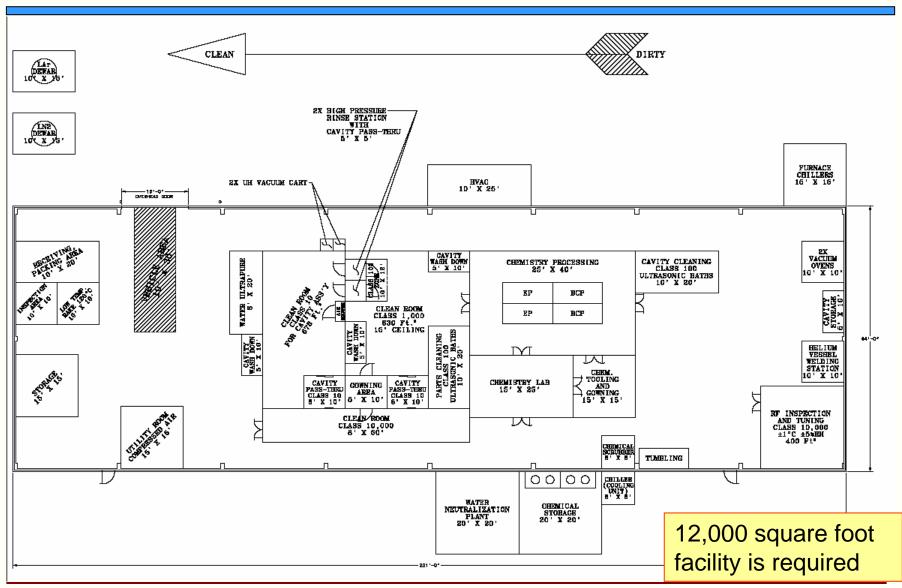
Cavity Processing Facility Features



- Separate chemical storage building
- Chemistry laboratory for small samples and pre-EBW etching
- Wet station area for component cleaning prior to bringing into clean rooms
- Class 1000 clean room housing major chemical processing equipment (EP and BCP cabinets, etc.)
- Exhaust fume scrubber
- Acid neutralization system
- Ultra Pure Water (UPW) system
- High Pressure Rinse (HPR) stations
- High and low temperature furnaces
- RF inspection and Automated cavity tuning system
- Class 10 clean room for final prep of cavities prior to VTS
- High purity gaseous argon and nitrogen systems
- TIG welding station for helium vessel installation
- Ultra clean vacuum pumping system and leak checking systems

CPF Floor Plan at MW





CPF Funding Requirements



| Infrastructure | | M&S | | SWF | | Total with Indirect | |
|--|----|--------|----|--------|----|---------------------|--|
| | | | | | | | |
| Cavity Fabrication Infrastructure | \$ | 3,000 | \$ | 675 | \$ | 4,380 | |
| Cavity Processing Facilities | \$ | 11,100 | \$ | 4,590 | \$ | 18,945 | |
| Vertical Test Stand (VTS 2 & 3) | \$ | 2,625 | \$ | 1,845 | \$ | 5,475 | |
| Horizontal Test Stand (HTS 2) | \$ | 1,220 | \$ | 1,057 | \$ | 2,805 | |
| Cavity/Cryomodule Assembly Facilties (CAF_MP9 & ICB) | \$ | 690 | \$ | 270 | \$ | 1,158 | |
| NML Facility (ILCTA_NML) | \$ | 18,270 | \$ | 23,220 | \$ | 51,700 | |
| Cryogenics for Test Facilities | \$ | 10,690 | \$ | 950 | \$ | 13,692 | |
| Cryomodule Test Stand | \$ | 5,400 | \$ | 2,970 | \$ | 10,180 | |
| Material R&D | \$ | 870 | \$ | 722 | \$ | 1,960 | |
| Illinois Accelerator Research Center | \$ | 20,000 | \$ | 4,050 | \$ | 28,605 | |
| Grand Total (\$k) | \$ | 73,865 | \$ | 40,349 | \$ | 138,900 | |

| Item | \$K |
|---------------------------|-----------------|
| M&S: SWF: | 11,100 4,590 |
| Grand Total w/o Indirect: | · |

Grand Total with Indirect:

Assumptions

- •Facility is located on FNAL site
- •3 year schedule from inception to completion and fully operational
- •Funding profile assumes 1/3 TPC available each fiscal year

18,945

CPF Itemized (Direct) Cost Estimate



| Item | | 1&S Costs | Labor | SWF Total | | tal Cost | | |
|--|-----|--------------|---------|-----------|-------|----------|--------|--|
| | \$K | | FTE*yrs | | \$K | | \$K | |
| Building Preparation | \$ | 250 | 0.5 | \$ | 68 | \$ | 318 | |
| Building Utility | \$ | 250 | 2.5 | \$ | 338 | \$ | 588 | |
| Infrastructure | 9 | 230 | 2.3 | Ф | 336 | Ф | 300 | |
| Clean Rooms | \$ | 1,000 | 0.5 | \$ | 68 | \$ | 1,068 | |
| Ultra-Pure Water | \$ | 150 | 1.5 | \$ | 203 | \$ | 353 | |
| System | | | | Ė | | | | |
| Clean Room Hardware | \$ | 150 | 1.25 | \$ | 169 | \$ | 319 | |
| Ultrasonic Cleaning | \$ | 150 | 0.5 | \$ | 68 | \$ | 218 | |
| Tanks | | | | · · | 00 | Ψ | 210 | |
| Vacuum Furnaces (2) | \$ | 1,000 | 0.25 | \$ | 34 | \$ | 1,034 | |
| Lo temp.furnaces (2) | \$ | 200 | 1 | \$ | 135 | \$ | 335 | |
| Cavity Tuning Devices and RF test equipment & fixtures | \$ | 1,000 | 1.25 | \$ | 169 | \$ | 1,169 | |
| HPR Systems (3) | \$ | 1,200 | 1.25 | \$ | 169 | \$ | 1,369 | |
| EP Systems (3) | \$ | 1,600 | 1.75 | \$ | 236 | \$ | 1,836 | |
| BCP Systems (2) | \$ | 1,000 | 1.75 | \$ | 169 | \$ | 1,169 | |
| Tumbling (2) | \$ | 500 | 1.23 | \$ | 135 | \$ | 635 | |
| Chemistry Lab | \$ | 450 | 4 | \$ | 540 | \$ | 990 | |
| Chemistry storage, | Ф | 430 | 4 | Ф | 340 | ф | 990 | |
| preparation, treatment infrastructure | \$ | 1,000 | 1.25 | \$ | 169 | \$ | 1,169 | |
| Vacuum Equipment and Hardware | \$ | 400 | 1.25 | \$ | 169 | \$ | 569 | |
| TIG Welding Machines, fixtures | \$ | 150 | 0.75 | \$ | 101 | \$ | 251 | |
| Miscellaneous Fixtures and Equipment | \$ | 400 | 4 | \$ | 540 | \$ | 940 | |
| Monitoring, controls, HMI integration | \$ | 250 | 3.25 | \$ | 439 | \$ | 689 | |
| ES&H preparation | | | 5 | \$ | 675 | \$ | 675 | |
| Totals | \$ | 11,100 | 34 | \$ | 4,590 | \$ | 15,690 | |

Cost Drivers

- Clean Rooms (Classes 10, 100, & 1000)
- Vacuum Hi Temp Bake Furnaces
- Cavity Tuning Devices & RF test equipment
- HPR Systems
- EP Systems
- BCP Systems
- Chemistry Storage, Preparation & Treatment Infrastructure

3 Year CPF Procurement Plan



Year One

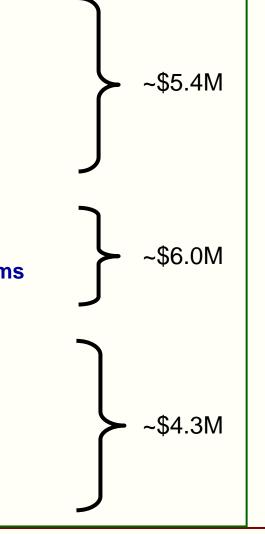
- Prep building for CPF, inc. utility infrastructure
- Procure & install clean rooms
- Procure clean room hardware
- Procure high and low temp. vacuum furnaces
- Procure & install UPW system
- Procure & install ultrasonic cleaning tanks
- Procure cavity tuning system

Year Two

- Procure EP and BCP systems
- Procure HPR systems
- Procure mechanical polishing (tumbling) systems
- Procure chemistry lab equipment

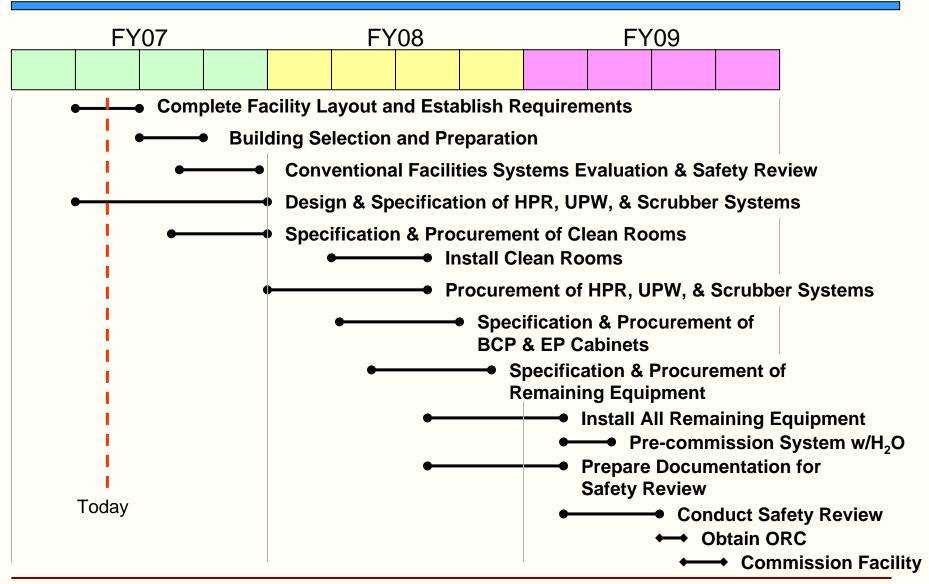
Year Three

- Procure & install scrubber system & treatment infrastructure
- Procure vacuum equipment & hardware
- Install all remaining equipment
- ES&H preparation
- Conduct safety review
- Commission facility



CPF Schedule Timeline





Alternative: An Off-Site CPF

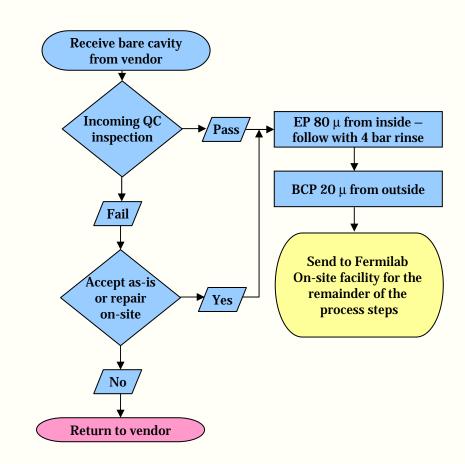


- A contract could be written for the design, construction, and operation of an off-site facility located very near FNAL.
- Facility would be financed by ILC funds and owned by government, but operated by industry
- Advantages:
 - Operation by an <u>experienced</u> electropolishing industrial firm using their manpower
 - Significantly reduces the need for large quantites of nasty chemicals on FNAL site
 - Initiates the industrialization program cavity processing
- Unknown total cost, estimate ~ \$6M due to the cost of a building (either leased or purchased)

Off-Site CPF Scope of Work

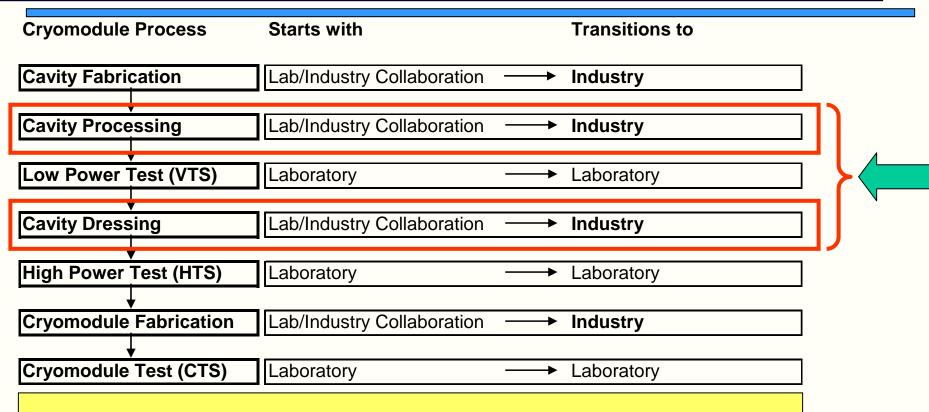


- Perform initial cavity inspection
- Perform bulk chemistry operations
 - Internal 80u EP
 - External 20u BCP
- Possibly include HPR;
 otherwise, ship cavity
 to FNAL in container
 filled with UPW



Development of Industry





The technology for cavity fabrication & processing, cavity dressing and cryomodule fabrication will be transferred to Industry.

Cryogenic testing of cavities and cryomodules along with beam tests will remain the responsibility of US laboratories.

Conclusion



- The combined total process capacity of present U.S. cavity processing facilities has been shown to be inadequate to handle the anticipated near term demands.
- A concept for a new facility (CPF) capable of meeting the ILC pre-production demands has been presented. Development of the facility specification and design is underway at FNAL.
- If located on the Fermilab site, the CPF could be completed in ~2 years at a total cost of \$15.7M.
- Splitting the CPF along the lines of completing the bulk chemistry processing in an off-site facility may be advantageous and merits further investigation